

Notice of References Cited	Application/Control No. 10/567,138		Applicant(s)/Patent Under Reexamination SALVERMOSER ET AL.	
	Examiner MICHAEL MASKELL		Art Unit 2881	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-6,052,401 A	04-2000	Wieser et al.	372/74
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*	D	US-2002/0031157 A1	03-2002	Heist et al.	372/55
*	E	US-6,400,089 B1	06-2002	Salvermoser et al.	315/111.81
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NON-PATENT DOCUMENTS

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	U	El-Habachi, et al ("Emission of excimer radiation from direct current, high-pressure hollow cathode discharges" Appl. Phys. Lett., Vol. 72., No. 1, pp. 22-24, 5 January 1998).
	V	Switkes, et al "Imaging of 1-nm-thick films with 193-nm microscopy," Optics Letters, 26:15 pp. 1182-1184, August 1, 2001.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.